

# Electronic Acknowledgement Receipt

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<b>EFS ID:</b>	1193633
<b>Application Number:</b>	10598933
<b>Confirmation Number:</b>	2213
<b>Title of Invention:</b>	Semiconductor wafer inspection device and method
<b>First Named Inventor:</b>	Fumi Nabeshima
<b>Customer Number:</b>	44719
<b>Filer:</b>	Joseph Patrick Farrar
<b>Filer Authorized By:</b>	
<b>Attorney Docket Number:</b>	PA214WP002
<b>Receipt Date:</b>	14-SEP-2006
<b>Filing Date:</b>	
<b>Time Stamp:</b>	21:19:36
<b>Application Type:</b>	U.S. National Stage under 35 USC 371
<b>International Application Number:</b>	PCT/JP05/12345

## Payment information:

Submitted with Payment	yes
Payment was successfully received in RAM	\$900
RAM confirmation Number	753
Deposit Account	503546

## File Listing:

Document Number	Document Description	File Name	File Size(Bytes)	Multi Part	Pages
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1	Drawings	fig01-fig06.pdf	494922	no	6
<b>Warnings:</b>					
<b>Information:</b>					
2	Application Data Sheet	ADSKomatsuElec.pdf	412012	no	4
<b>Warnings:</b>					
<b>Information:</b>					
This is not an USPTO supplied ADS fillable form					
3	Assignee showing of ownership per 37 CFR 3.73(b).	US_Assignment.pdf	72337	no	1
<b>Warnings:</b>					
<b>Information:</b>					
4	Oath or Declaration filed	US_declararion.pdf	229043	no	4
<b>Warnings:</b>					
<b>Information:</b>					
5	Transmittal letter	NewUtilityPatentApplication.pdf	41043	no	2
<b>Warnings:</b>					
<b>Information:</b>					
6		PKM050074PCT_SPEC.pdf	5050056	yes	39
	<b>Multipart Description</b>				
	<b>Doc Desc</b>		<b>Start</b>	<b>End</b>	
	Specification		1	34	
	Claims		35	38	
	Abstract		39	39	
<b>Warnings:</b>					
<b>Information:</b>					
7	Transmittal letter	sb0005_fillTransmittalFormInitalFiling.pdf	269460	no	2
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<b>Information:</b>					

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## Electronic Patent Application Fee Transmittal

**Application Number:**

**Filing Date:**

Adjustment date: 01/18/2008 SDIRETA1  
 09/15/2006 INTEFSW 00000753 503546 10598933  
 01 FC:1631 300.00 CR  
 02 FC:1642 400.00 CR  
 03 FC:1633 200.00 CR

**Title of Invention:** 10598933

Semiconductor wafer inspection device and method

8/2008 SDIRETH1 00000001 503546  
 C:1011 300.00 DA  
 C:1111 500.00 DA  
 C:1311 200.00 DA

**First Named Inventor:**

Fumi Nabeshima

**Filer:**

Joseph Patrick Farrar

**Attorney Docket Number:**

PA214WP002

Filed as Large Entity

### U.S. National Stage under 35 USC 371 Filing Fees

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
<b>Basic Filing:</b>				
National Stage Fee	1631	1	300	300
Natl Stage Search Fee - Report provided	1642	1	400	400
National Stage Exam - all other cases	1633	1	200	200

**Pages:**

**Claims:**

**Miscellaneous-Filing:**

**Petition:**

**Patent-Appeals-and-Interference:**

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